

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:) Confirmation No. 9528
Koichiro TANAKA)
Application No. 10/769,820) Examiner: Samuel Heinrich
Filed: February 3, 2004) Group Art Unit: 1725
For: LASER IRRADIATION STAGE, LASER)
IRRADIATION OPTICAL SYSTEM, LASER)
IRRADIATION APPARATUS, LASER)
IRRADIATION METHOD, AND METHOD OF)
MANUFACTURING A SEMICONDUCTOR)
DEVICE) Date: November 8, 2006

AMENDMENT

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed August 8, 2006, please amend the above-identified patent application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 7 of this paper.